

UNITED STATES PATENT AND TRADEMARK OFFICE

UNITED STATES DEPARTMENT OF COMMERCE United States Patent and Trademark Office Address: COMMISSIONER FOR PATENTS P.O. Box 1450 Alexandria, Virginia 22313-1450 www.uspto.gov

APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
09/966,692	09/28/2001	Tsutomu Yamada	YKI-0078	4078
23413	7590 06/09/2005	5 EXAMINER		INER
CANTOR COLBURN, LLP 55 GRIFFIN ROAD SOUTH			MULPURI, SAVITRI	
BLOOMFIELD, CT 06002			ART UNIT	PAPER NUMBER
	•		2812	

DATE MAILED: 06/09/2005

Please find below and/or attached an Office communication concerning this application or proceeding.

gr

	Application No.	Applicant(s)				
Office Action Comment	09/966,692	YAMADA ET AL.				
Office Action Summary	Examiner	Art Unit				
	Savitri Mulpuri	2812				
The MAILING DATE of this communication app Period for Reply	ears on the cover sheet with the c	orrespondence address				
A SHORTENED STATUTORY PERIOD FOR REPLY THE MAILING DATE OF THIS COMMUNICATION. - Extensions of time may be available under the provisions of 37 CFR 1.13 after SIX (6) MONTHS from the mailing date of this communication. - If the period for reply specified above is less than thirty (30) days, a reply - If NO period for reply is specified above, the maximum statutory period w - Failure to reply within the set or extended period for reply will, by statute, Any reply received by the Office later than three months after the mailing earned patent term adjustment. See 37 CFR 1.704(b).	of (a). In no event, however, may a reply be time within the statutory minimum of thirty (30) days ill apply and will expire SIX (6) MONTHS from cause the application to become ABANDONE	ely filed s will be considered timely. the mailing date of this communication. O (35 U.S.C. § 133).				
Status						
1) Responsive to communication(s) filed on 3/30/3	<u>3005</u> .					
2a) ☐ This action is FINAL . 2b) ☒ This	•					
3) Since this application is in condition for allowan	3) Since this application is in condition for allowance except for formal matters, prosecution as to the merits is					
closed in accordance with the practice under E	closed in accordance with the practice under Ex parte Quayle, 1935 C.D. 11, 453 O.G. 213.					
Disposition of Claims						
4)⊠ Claim(s) <u>7,9,20-24,30,32,34</u> is/are pending in the application.						
4a) Of the above claim(s) is/are withdrawn from consideration.						
5) Claim(s) is/are allowed.						
6) Claim(s) 7,9,20-24,30,32,34 is/are rejected.						
7) Claim(s) is/are objected to.						
8) Claim(s) are subject to restriction and/or	election requirement.					
Application Papers						
9) ☐ The specification is objected to by the Examine						
10) ☐ The drawing(s) filed on is/are: a) ☐ accepted or b) ☐ objected to by the Examiner.						
Applicant may not request that any objection to the						
Replacement drawing sheet(s) including the correcti	* * * * * * * * * * * * * * * * * * * *					
11) ☐ The oath or declaration is objected to by the Ex	aminer. Note the attached Office	Action or form P10-152.				
Priority under 35 U.S.C. § 119						
 12) Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f). a) All b) Some * c) None of: 1. Certified copies of the priority documents have been received. 2. Certified copies of the priority documents have been received in Application No 3. Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)). 						
* See the attached detailed Office action for a list of the certified copies not received.						
Attachment(s)						
1) Notice of References Cited (PTO-892)	4) Interview Summary					
2) Notice of Draftsperson's Patent Drawing Review (PTO-948) 3) Information Disclosure Statement(s) (PTO-1449 or PTO/SB/08)	Paper No(s)/Mail Da 5) Notice of Informal P	ate atent Application (PTO-152)				
Paper No(s)/Mail Date <u>3/30/3005</u> .	6) Other:					

DETAILED ACTION

This action is in response to the applicant's communication filed on 3/30/3005.

Claim Rejections - 35 USC § 102

The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless -

- (b) the invention was patented or described in a printed publication in this or a foreign country or in public use or on sale in this country, more than one year prior to the date of application for patent in the United States.
- (e) the invention was described in (1) an application for patent, published under section 122(b), by another filed in the United States before the invention by the applicant for patent or (2) a patent granted on an application for patent by another filed in the United States before the invention by the applicant for patent, except that an international application filed under the treaty defined in section 351(a) shall have the effects for purposes of this subsection of an application filed in the United States only if the international application designated the United States and was published under Article 21(2) of such treaty in the English language.

Claims 7,9,20-24,30,32,34 are rejected under 35 U.S.C. 102(e) as being anticipated by Ikuko et al (6,255,775)

lkuko et al discloses a method of forming an individually patterned layer in plurality of region of the substrate, comprising the steps of:

disposing between the substrate and layer material source, a mask including an opening corresponding to one or more of the plurality region where said layer is formed;

causing a material from the layer material source to attach to a first region of the substrate through the opening, while relative positions of the substrate, the mask, the material source are set to a final positional relationship;

Application/Control Number: 09/966,692 Page 3

Art Unit: 2812

causing relative movement between the mask, material source and the substrate the substrate to change relative positions of the substrate, the mask and the source material; from the first positional relationship to the second positional relationship;

causing the material to attach to a second region of the substrate through the opening, while relative positions of the substrate, the mask, and the source material are set to second positional relationship (see fig. 9 a-9d and related description ant).

Ikuko et al further discloses linearly extending source "11, 12, 13" plurality of material sources, elongated in a direction perpendicular to a direction of the relative movement between the mask, material source and the substrate. Ikuko et al teaches electroluminescent materials deposited on the substrate "5,6,7" (see fig. 3 and related description). With respect to claims 11, 33, Ikuko et al further teach emissive material layer for each color for each plurality of pixels.

lkuko et al teaches a mask "9" having one or more holes and having smaller are than the substrate "1 (see fig.1 or fig. 5 a-5c).

Claim Rejections - 35 USC § 103

The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

⁽a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.

The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.

Claim 24 is rejected under 35 U.S.C. 103(a) as being unpatentable over Ikuko (6,255,775) in combination with Tonucci et al (6,087,274)

lkuko et al discloses a method of forming an individually patterned layer in plurality of region of the substrate, comprising the steps of:

disposing between the substrate and layer material source, a mask including an opening corresponding to one or more of the plurality region where said layer is formed;

causing a material from the layer material source to attach to a first region of the substrate through the opening, while relative positions of the substrate, the mask, the material source are set to a final positional relationship;

causing relative movement between the mask, material source and the substrate the substrate to change relative positions of the substrate, the mask and the source material; from the first positional relationship to the second positional relationship;

causing the material to attach to a second region of the substrate through the opening, while relative positions of the substrate, the mask, and the source material are set to second positional relationship (see fig. 9 a-9d and related description ant).

Application/Control Number: 09/966,692

Art Unit: 2812

Ikuko et al further discloses linearly extending source "11, 12, 13" plurality of material sources, elongated in a direction perpendicular to a direction of the relative movement between the mask, material source and the substrate. Ikuko et al teaches electroluminescent materials deposited on the substrate "5,6,7" (see fig. 3 and related description). With respect to claims 11, 33, Ikuko et al further teach emissive material layer for each color for each plurality of pixels.

Page 5

Hirano et al also discloses all the claimed limitations including forming plurality of electroluminescent materials "25 a, 25 b, 25 c" in different regions by using single mask by sliding the mask with respect fixed substrate (see fig. 2 A-2F and fig 3. col. 7, lines 46-67).

Ikuko et al do not disclose using mask made of semiconductor material.

Tonucci et al teaches depositing nanosize patterning process by providing silicon carbide substrate with plurality of holes and depositing the material through the holes with accuracy and precision by relative movement of the mask and the substrate. Tonucci et al further discloses using the position technique for organic materials. (see col. 60-67, fig. 2 B-2 C and claims 2, 23). It would have been obvious to one of ordinary skill in the art to use silicon carbide mask with plurality of openings to deposit material over the substrate in the invention of Ikuko et la or Hirano et al because of the advantage of depositing in small area of the large substrate with accuracy and precision as taught by Tonucci et al.

Application/Control Number: 09/966,692 Page 6

Art Unit: 2812

Response to Arguments

Applicant's arguments with respect to claims 7,9,20-24,30,32,34 have been considered but are moot in view of the new ground(s) of rejection.

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Savitri Mulpuri whose telephone number is 571-272-1677. The examiner can normally be reached on Mon-Fri from 8 a.m. to 4.30 p.m.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Michael Lebentritt, can be reached on 571-272-1873. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

Savitri Mulpuri Primary Examiner

Art Unit 2812